

Title (en)  
MICROMECHANICAL PRESSURE SENSOR

Title (de)  
MIKROMECHANISCHER DRUCKSENSOR

Title (fr)  
CAPTEUR DE PRESSION MICROMÉCANIQUE

Publication  
**EP 2235491 A1 20101006 (DE)**

Application  
**EP 08869465 A 20081222**

Priority  
• EP 2008068146 W 20081222  
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Abstract (en)  
[origin: WO2009087055A1] The invention relates to a micromechanical pressure sensor with a substrate and a membrane, on which piezoelectric sensor elements are located. The aim of the invention is to provide a pressure sensor which has minimal dimensions and in which torsional loads of the membrane are extensively avoided. This task is solved according to the invention by an arrangement in which the substrate has a frame (1), on which the membrane (2) is arranged, wherein a centrally arranged mass element (3) is located on the underside of the membrane (2) and the membrane (2) is in each case provided with two partial reinforcements (2.1, 2.2) on striated sections, located between frame 1 and the mass element (3).

IPC 8 full level  
**G01L 9/00** (2006.01)

CPC (source: EP)  
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Citation (search report)  
See references of WO 2009087055A1

Citation (examination)  
• WO 2007073994 A1 20070705 - BOSCH GMBH ROBERT [DE], et al  
• US 5068203 A 19911126 - LOGSDON JAMES H [US], et al  
• US 6255728 B1 20010703 - NASIRI STEVEN S [US], et al  
• DE 4021424 A1 19910124 - TELTOV GERAETE REGLER [DE]

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